

03500.015382.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

TAKAHARU KONDO ET AL.

Application No.: 09/866,665

Filed: May 30, 2001

For: SILICON-TYPE THIN  
FILM FORMATION  
PROCESS, SILICON TYPE  
THIN FILM, AND  
PHOTOVOLTAIC DEVICE

Examiner: Brian L. Mutschler

Group Art Unit: 1753

October 22, 2002

#  
7/A  
W.M.  
10/30/02

Commissioner for Patents  
Washington, D.C. 20231

RECEIVED  
OCT 25 2002  
TC 1100

AMENDMENT AND PETITION FOR EXTENSION OF TIME

Sir:

Applicants petition to extend the time for response to the Office Action dated May 9, 2002 to November 9, 2002. A check in the amount of \$920.00 for payment of the extension fee is enclosed. Please charge any additional fee required for the extension, and credit any overpayment, to Deposit Account 06-1205.

In response to the Office Action dated May 9, 2002, please amend the above-identified application as follows:

IN THE SPECIFICATION:

Please replace the Abstract of the Disclosure with the substitute Abstract of the Disclosure as follows:

10/24/2002 SSESHE1 00000074 09866665 920.00 DP  
01 FC:1253